

AMENDMENTS TO THE CLAIMS:

Kindly amend claims 1 and 5, as shown below.

This listing of claims will replace all prior versions and listings of claims in the Application:

Claim 1 (currently amended). A measuring instrument for noncontact measurement of conductivity of a silicon wafer using a microwave, the measuring instrument comprising:

an oscillator operating at a frequency not more than 100 GHz for oscillating the microwave;

a circulator connected to the oscillator;

a horn antenna connected to the circulator, the horn antenna transmitting the microwave to an upper surface of the silicon wafer and receiving a reflected wave from [[a]] the upper surface of the silicon wafer;

a detector connected to said circulator, the detector outputting a voltage proportional to a square of magnitude of the wave from the upper surface of said silicon wafer; and

a computer for computing conductivity of said silicon wafer from said voltage.

Claim 2 (previously presented). A measuring instrument according to claim 1, wherein said circulator is connected to the oscillator through an isolator.

Claim 3 (previously presented). A measuring instrument according to claim 1, wherein a frequency of the microwave oscillating in said oscillator is 94 GHz.

Claim 4 (previously presented). A measuring instrument according to claim 2, wherein a frequency of the microwave oscillating in said oscillator is 94 GHz.

HAYES SOLOWAY P.C.
3450 E. SUNRISE DRIVE,
SUITE 140
TUCSON, AZ 85718
TEL. 520.882.7623
FAX. 520.882.7643

175 CANAL STREET
MANCHESTER, NH 03101
TEL. 603.668.1400
FAX. 603.668.8567

Claim 5 (currently amended). A conductivity measuring instrument for noncontact measuring of ~~conductivity~~ conductivity of a silicon wafer using a microwave, the measuring instrument comprising, in combination:

- an oscillator for oscillating of the microwave;
- a circulator connected to the oscillator;
- a horn antenna connected to the circulator, the horn antenna transmitting the microwave to the silicon wafer and receiving a reflected wave from a surface of the silicon wafer;
- a detector connected to said circulator, the detector outputting a voltage proportional to a square of magnitude of the reflected wave; and
- a computer for computing conductivity of said silicon wafer from said voltage as a function of an absolute value of reflectance.

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